

Fig. 1

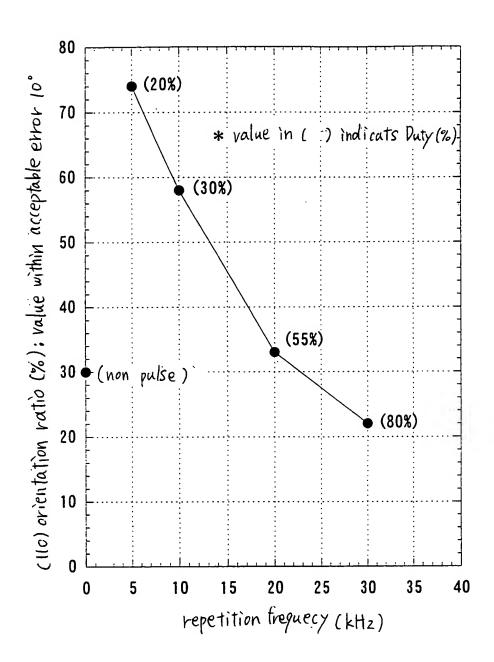


Fig. 2

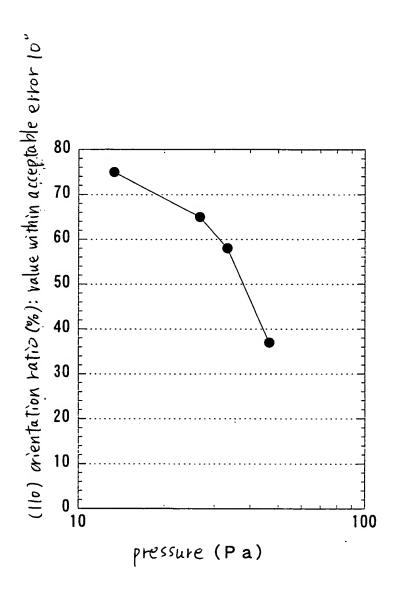


Fig. 3

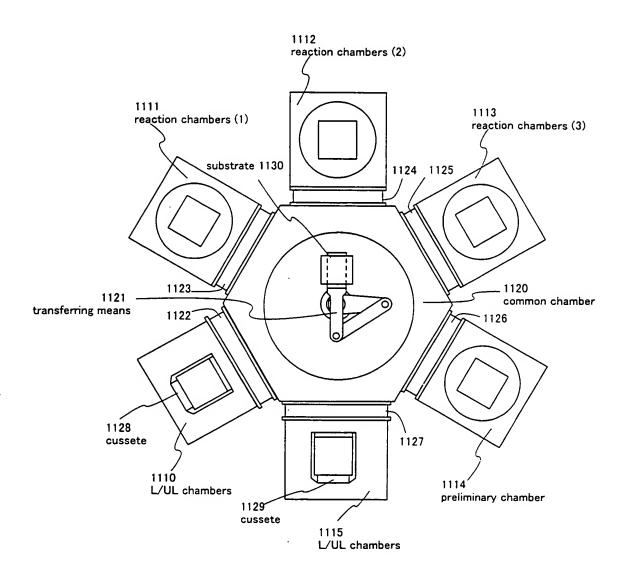


Fig. 4

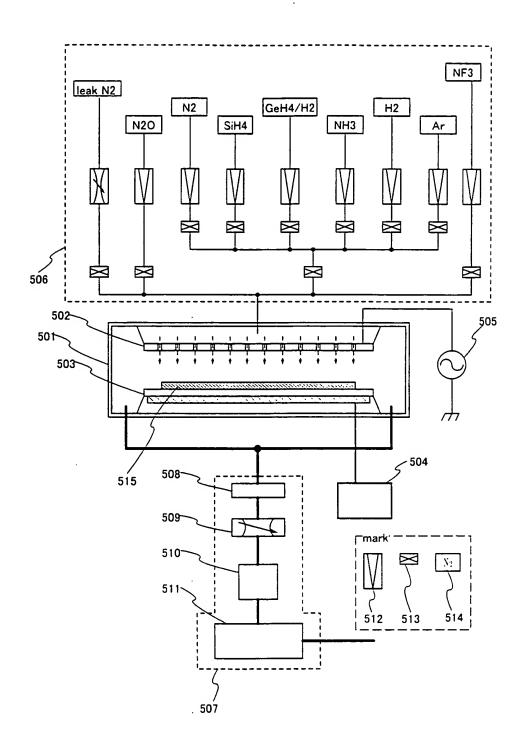


Fig. 5

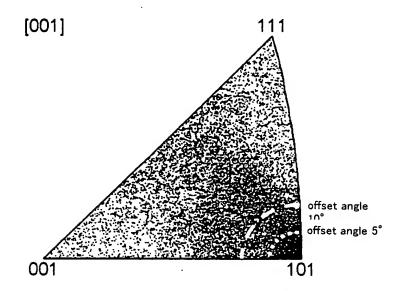


Fig. 6A plotting all of the measurement points in the mapping measurement

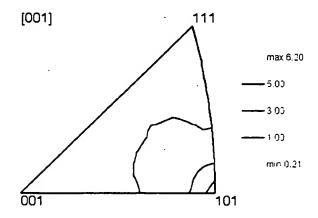
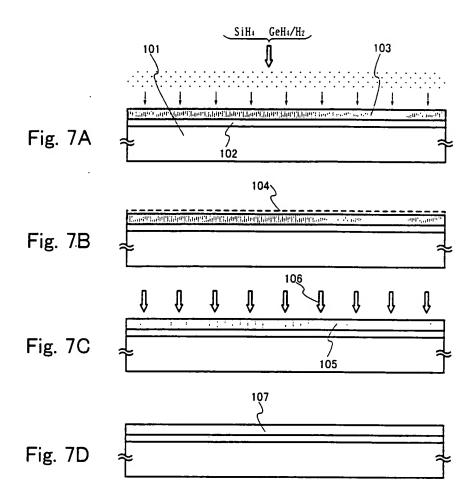
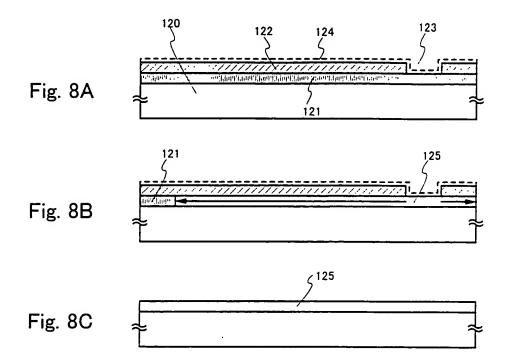


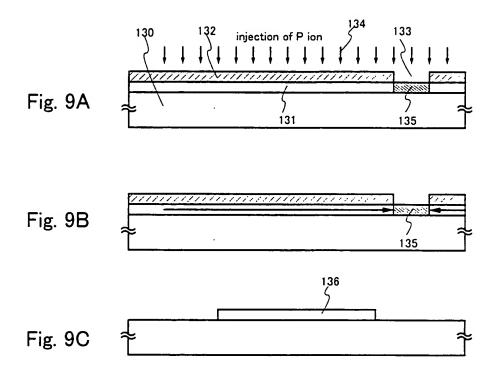
Fig. 6B example of expressing as contour an orientation distribution function to specific index.



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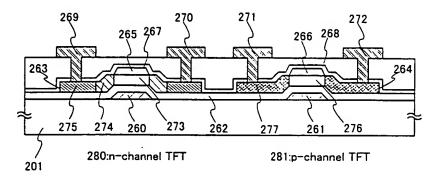
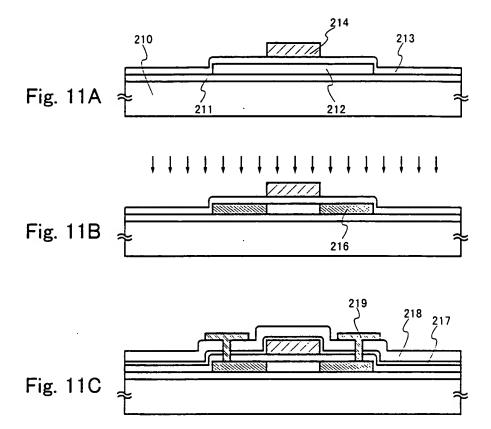
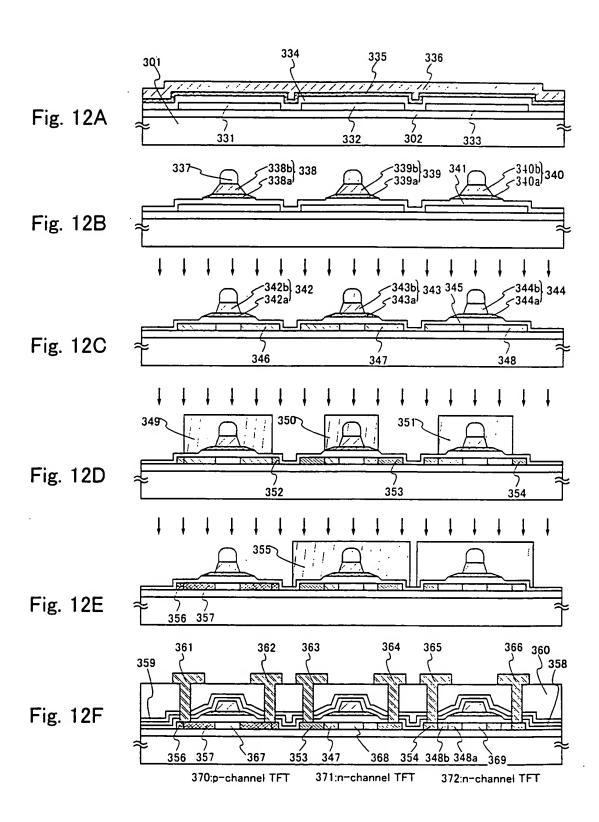
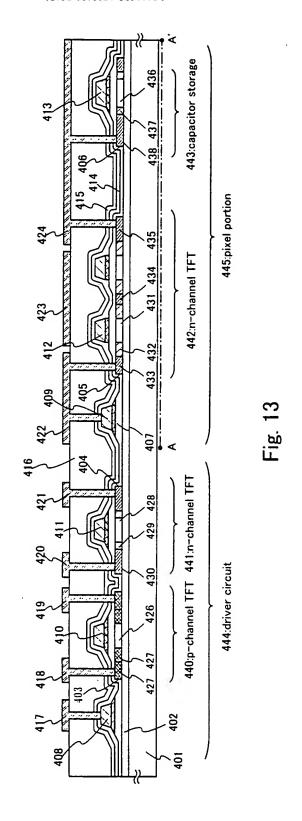


Fig. 10







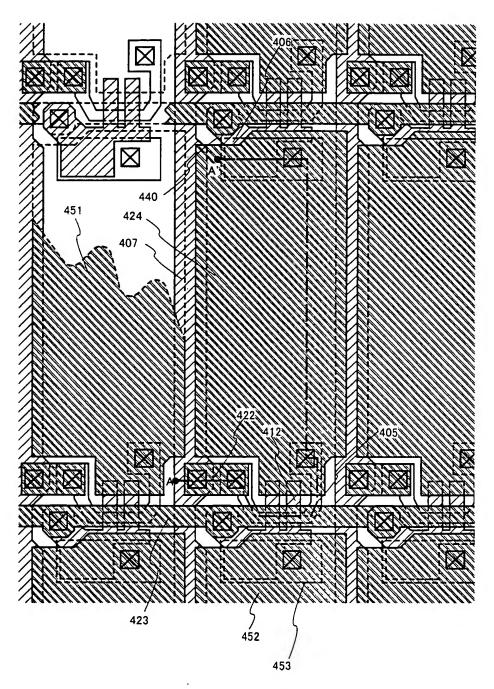
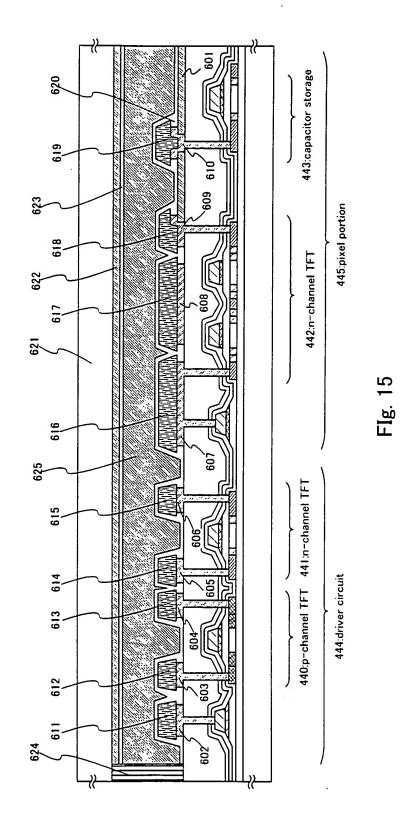
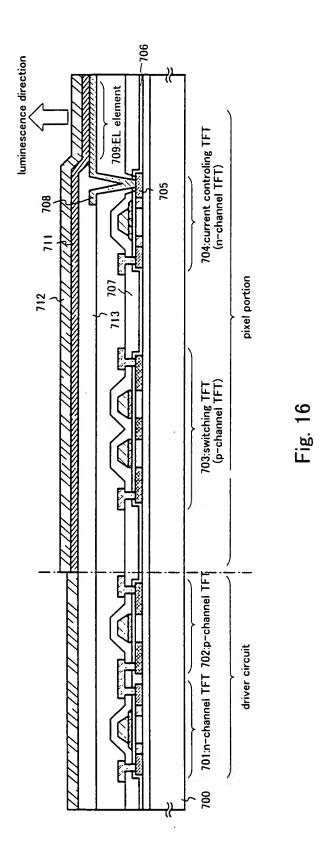


Fig. 14





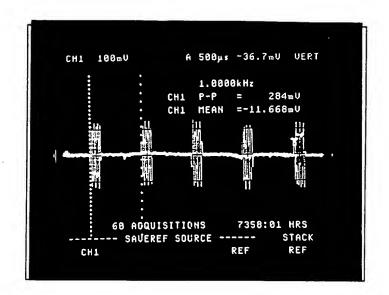


Fig. 17A

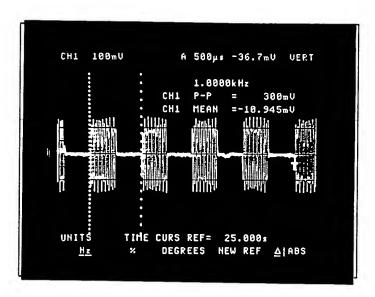


Fig. 17 B

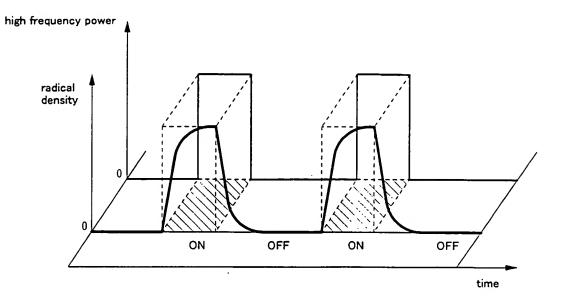


Fig. 18

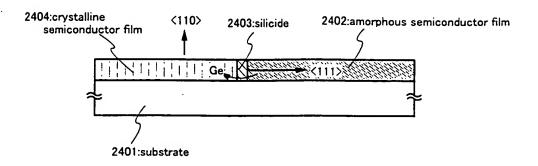


Fig. 19

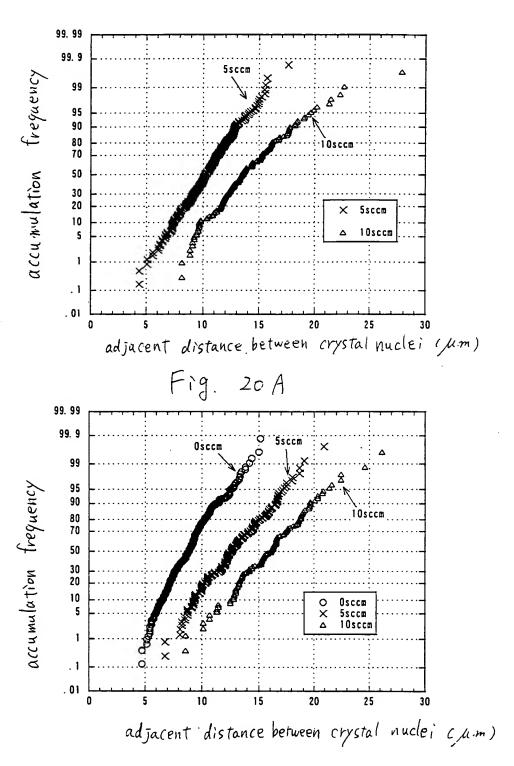


Fig. 2013

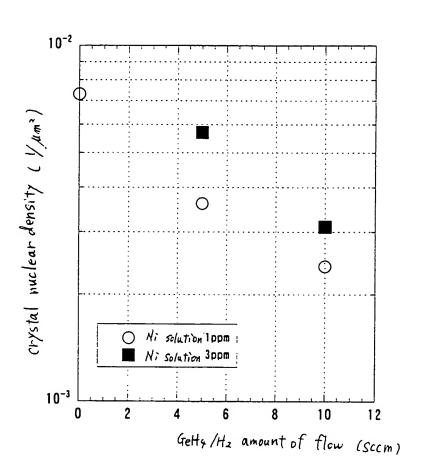
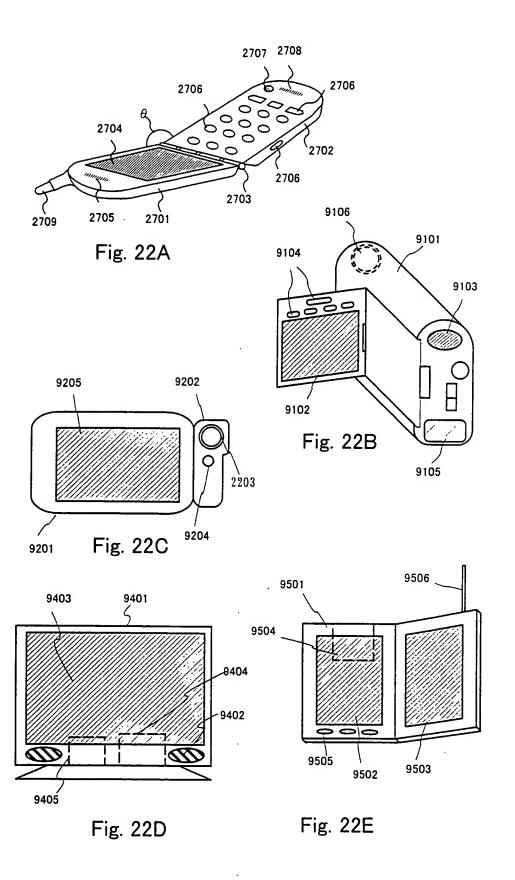
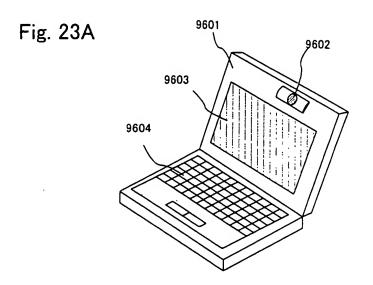
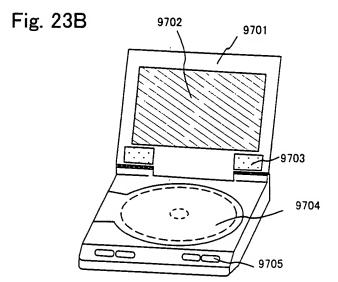
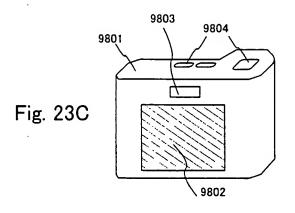


Fig. 21









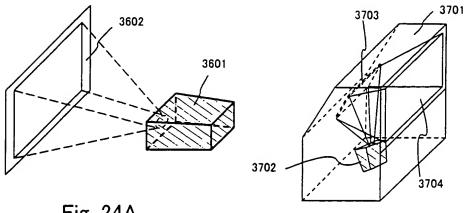


Fig. 24A

Fig. 24B

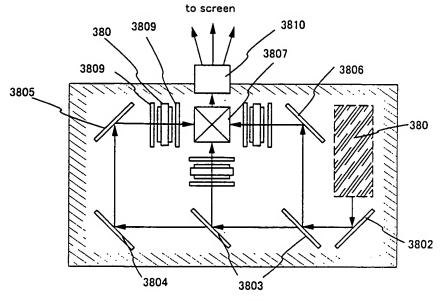


Fig. 24C

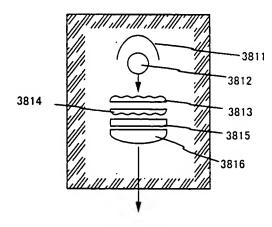


Fig. 24D

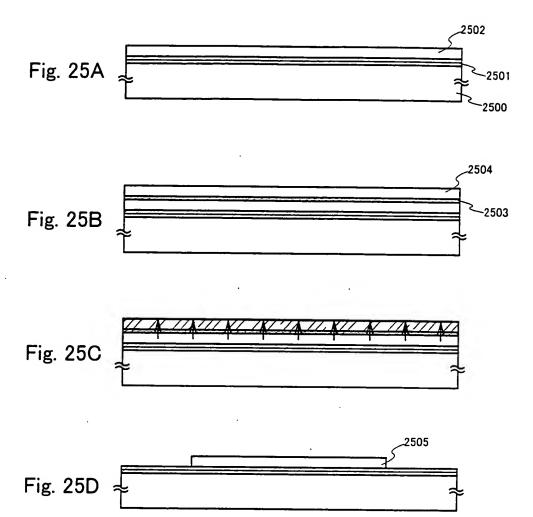


Fig. 26 A

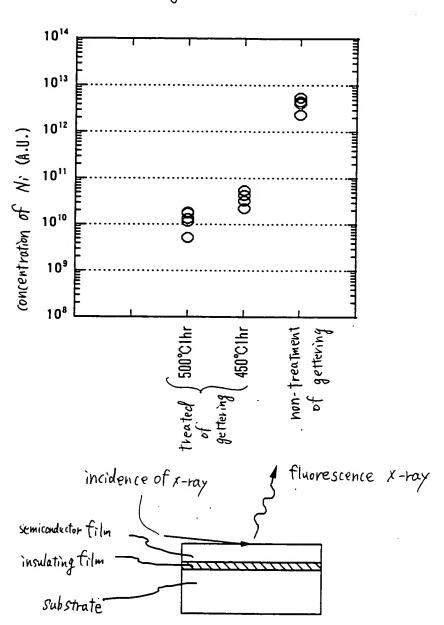


Fig. 26B